

ABSTRACT

A connecting device, a substrate heat treatment unit, and a coating and developing apparatus are provided. The connecting device described above is used for connecting adjacent chambers. Vent holes are provided on the opposing sides of adjacent chambers, and a preset spacing is provided between adjacent chambers. The connecting device is of a tubular structure and is configured to be capable of extending and retracting in the length direction of the connecting device; in an extended state, the connecting device has a first preset length longer than the preset spacing; in a retracted state, the connecting device has a second preset length shorter than or equal to the preset spacing, so that the connecting device can be installed between adjacent chambers, and the two ends of the connecting device are respectively connected to the corresponding vent holes for forming an exhaust channel between adjacent chambers. By adopting the connecting device in the substrate heat treatment unit, the technical effects of reducing the overall size of the heat treatment unit and facilitating maintenance are achieved.